Sent By: O'BANION & RITCHEY LLP;



CERTIFICATE OF TR Applicant(s): WENBING Y		CSIMILE (37 CFR 1.8)	Dacket No.
Serial No. 09/927,428	Filing Date 08/09/2001	Examiner DEO, DUY VU NGUYEN	Group Art Unit 1765
Invention: METHOD FOR	NANOMACHINING HIG	H ASPECT RATIO STRUCTURES	
I hereby certify that this is b ing facsimile transmitte	d to the United States Pat		703-872-92 <b>1</b> 0
on 20 JUNE 200 (Date)			
(2rate)			
	_	JOHN P. O'BANI (Typed or Printed Name of Person Sig	
		(Signature)	
	Note: Each paper mus	t have its own certificate of mailing.	

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Jun-20-03 17:51;

Inventor:

WENBING YUN; ET AL.

Serial No.: Filed:

Sent By: O'BANION & RITCHEY LLP;

09/927,428 08/09/2001

For:

METHOD FOR NANOMACHINING HIGH ASPECT RATIO

STRUCTURES

Group No.: 1765

Examiner:

DEO, DUY VU NGUYEN

Docket No.: LBL-IB-1498

**Commissioner for Patents** P.O. Box 1450 Alexandria, VA 22213-1450

## **AMENDMENT**

Dear Sir:

In response to the Office Action mailed on February 20, 2003, please amend the above-identified U.S. patent application as follows:

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S/N 09/927,428